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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application

SC/Serial No.: SEE SCHEDULE A
Filed: SEE SCHEDULE A
Title: SEE SCHEDULE A

PATENT APPLICATION

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Tina M. Galdos
Signature Date: December 17, 2002

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Sir:

I am the attorney of record for the patents and patent applications listed on Schedule A attached hereto. Please be notified that my address has changed to the following:

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Please send all future correspondence concerning the patent and patent applications listed on Schedule A to the above address.

Date: 12-17-02

By:

Respectfully submitted,

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SCHEDULE A**LIST OF ISSUED PATENTS**

Title	Filing Date	U.S. Serial No.	Issue Date	Patent No.	Old (BDSM) Attorney Docket No.	New Attorney Docket No.
Null Test Fourier Domain Alignment Technique for Phase-Shifting Point Diffraction Interferometer	1/12/1999	09/229,449	8/29/2000	6,111,646	015780-024	LBLL-01024US0
Phase-Shifting Point Diffraction Interferometer Mask Designs	10/21/1998	09/176,617	10/23/2001	6,307,635	015780-025	LBLL-01025US0
Phase-Shifting Point Diffraction Interferometer Grating Designs	10/21/1998	09/176,695	2/27/2001	6,195,169	015780-027	LBLL-01027US0
Phase-Shifting Point Diffraction Interferometer Focus-Aid Enhanced Mask	7/26/1999	09/361,780	11/21/2000	6,151,115	015780-028	LBLL-01028US0
Dual-Domain Point Diffraction Interferometer	4/27/1999	09/300,539	8/8/2000	6,100,978	015780-030	LBLL-01030US0
In Situ Alignment System for Phase Shifting Point-diffraction Interferometry	6/2/1999	09/324,903	9/12/2000	6,118,535	015780-031	LBLL-01031US0
Phase-Shifting Point Diffraction Interferometer Phase Grating Designs	10/14/1999	09/419,703	7/24/2001	6,266,147	015780-032	LBLL-01032US0
Interferometric At-Wavelength Flare Characterization of EUV Optical System	7/28/2000	09/627,533	5/15/2001	6,233,056	015780-033	LBLL-01033US0
Method of Fabricating Reflection-Mode EUV-Diffraction Elements	12/5/2000	09/730,970	5/21/2002	6,392,792	015780-039	LBLL-01039US0

SCHEDULE A**LIST OF PENDING PATENT APPLICATIONS**

Title	Filing Date	U.S. Serial No.	Old (BDSM) Attorney Docket No.	New (FDML) Attorney Docket No.
Method and Apparatus for Inspecting Reflection Masks for Defects	11/17/1998	09/193,198	015780-026	LBLL-01026US0
System for Interferometric Distortion Measurements That Define an Optical Path	5/11/2000	09/569,168	015780-029	LBLL-01029US0
Dual-Domain Lateral Shearing Interferometer	8/4/2000	09/632,631	015780-034	LBLL-01034US0
Hybrid Shearing and Phase-Shifting Point Diffraction Interferometer	7/17/2000	09/617,719	015780-035	LBLL-01035US0
Method of Fabricating Reflection-Mode EUV Diffusers	4/30/2001	09/846,150	015780-040	LBLL-01040US0
Apparatus for Generating Partially Coherent Radiation	8/30/2001	09/944,391	015780-041	LBLL-01041US0
A Holographic Illuminator for Synchrotron-Based Projection Lithography Systems	10/16/2001	09/981,500	015780-042	LBLL-01042US0
Synchrotron-Based EUV Lithography Illuminator Simulator	6/5/2002	10/163,479	015780-043	LBLL-01043US0
Diffractive Optical Element for Extreme Ultraviolet Wavefront Control	9/17/2001	09/956,160	015780-044	LBLL-01044US0